

SCHEDULE OF EVENTS

SUNDAY 3RD SEPTEMBER 2006

- 17.00 Registration
18.00 Drinks reception (Sponsored by EVG)
19.00 Dinner

MONDAY 4TH SEPTEMBER 2006

- 08.00 Registration and poster hanging, main campus
08.50 Welcome

- 09.00 **Invited Paper 1: Microfluidics: from Discrete Solutions to Integrated Microfluidic Platforms** 3
R Zengerle
University of Freiburg, Freiburg, Germany
- 10.00 **POSTER INTRODUCTIONS A**
- A.1 **Sagging Control of LTCC-Membranes Using a Statistical Model** 9
H Bartsch de Torres, M Hintz, T Thelemann, M Hoffman
Technische Universitat Ilmenau, Germany
- A.2 **Systematic Study of the RF Properties of Micro-Electromechanical RF Resonators for Sensor Applications** 13
K Brueckner, F Will, K Tonisch, V Cimalla, O Ambacher, R Stephan, M E Hein
Technical University of Ilmenau, Germany
- A.3 **Nano-Imprinting Lithography-A Novel Way to Fabricate Diffractive Barcoded Particles** 17
S Banu, S Birtwell, G Galitonov, A Whitton, Y Chen, N Zheludev, H Morgan
University of Southampton, UK and Rutherford Appleton Laboratory, Didcot, Oxon
- A.4 **Focused-Ion-Beam-Assisted Tuning of Thin-Film Bulk Acoustic Wave Resonators** 21
H Campanella, J Esteve, A Romano-Rodriguez, J Montserrat, A Uranga, N Barniol
Centro Nacional de Microelectronica Barcelona, Universitat de Barcelona, Universitat Autònoma de Barcelona, Spain
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J H Correia, B Wessling, N S Dias, H R Silva, W Mokwa, U Schnakenberg
University of Minho, Guimaraes, Portugal
RWTH Aachen University, Aachen, Germany
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M Dijkstra, T S J Lammerink, R J Wiegerink, M Elwenspoek
University of Twente, The Netherlands

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	<i>E M Yeatman</i> <i>Imperial College, London, UK</i>	

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	<i>J K Luo, Y Q Fu, H R Le, J A Williams, S M Spearing, W I Milne</i> <i>Department of Eng. Cambridge University, U. K.</i> <i>Division of Mechanical Eng. & Mechatronics, University of Dundee, U. K.</i> <i>School of Engineering Science, University of Southampton, U. K.</i>	
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TUESDAY 5TH SEPTEMBER 2006

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	<i>A M Shkel</i>	
	<i>University of California, Irvine, USA</i>	
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